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TI Reflecting layer of optical recording medium and sputtering
target for forming reflecting layer
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	TW 501112	B	20020901	TW 2001-90121736	20010903
	US 20040101781	A1	20040527	US 2003-363480	20031215
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AB	The invention relates to a reflecting layer of an optical recording medium having a recording layer, a reflecting layer, and a protecting layer on a substrate, wherein the reflecting layer is made of an alloy thin film comprising 99.7-73.0 weight of Cu as a primary component, 0.2-18.0 weight of Ag, and 0.1-9.0 weight of Ti and has a film thickness of 50-150 nm. A target for forming the reflecting layer is also claimed. The optical recording medium having the reflecting layer exhibits improved resistance while retaining high reflectance).				
RE.CNT 3	THERE ARE 3 CITED REFERENCES AVAILABLE FOR THIS RECORD				
	ALL CITATIONS AVAILABLE IN THE RE FORMAT				